

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN THE MATTER OF:

Jaehwan EUN, et al

SERIAL NO.: 10/539,883

FILED: June 17, 2005

ART UNIT: 1722

EXAMINER: Kunemund, Robert M.

CONFIRMATION NO.: 1957

FOR: Method For Preparation of Ferroelectric Single Crystal Film Structure Using  
Deposition Method

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Arlington, VA 22313-1450

S I R:

This is in response to the outstanding Office Communication dated June 4, 2007. The Commissioner is authorized to charge any fees required in the prosecution of this application to Deposit Account No. 503814.

Please amend the present application as follows: